

# Ultra-Fast Optical Response by InAlAs/InAs/InGaAs Pseudomorphic High Electron Mobility Transistors

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## 1. Introduction

High electron mobility transistors with a pseudomorphically strained InAs channel (InAs-PHEMTs) have superior electron transport properties and high electron density, which are due to a large conduction band discontinuity [1]. The current-gain cutoff frequency ( $f_i$ ) of 628 GHz [2] and the maximum oscillation frequency ( $f_{max}$ ) of 1.2 THz have been reported [1]. Recently, we have pointed out that the non-parabolicity of conduction band must be taken into account strictly when discussing the characteristics of HEMTs with the InAs channel [3]. In addition, we have demonstrated that these HEMTs can operate as not only a high speed transistor but an ultra-high speed optical receiver [4, 5]

In this work, we show the dependence of the optical response on the drain-to-source voltages ( $V_{DS}$ ) for InAs-PHEMTs and make clear the physical mechanism for the response time. To physically understand those optical responses, we estimated the minority carrier lifetime  $\tau$  using Auger recombination theory [6, 7]

## 2. Experiment

### 2.1. Device structure

We examined the pseudo-morphic channel of an InAs-PHEMT that was composed of the following layers: In<sub>0.53</sub>Ga<sub>0.47</sub>As (2 nm), InAs (3 nm), In<sub>0.7</sub>Ga<sub>0.3</sub>As (7 nm), and In<sub>0.53</sub>Ga<sub>0.47</sub>As (6 nm) [8]. Figure 1 shows an InAs-PHEMT structure we used. Since a lower growth temperature is required to grow the strained layers, we grew the pseudomorphic HEMTs at 673 K.

### 2.2. Experimental setup

Figure 2 shows the experimental setup we used for measuring the optical response. In this experiment, the optical pulse from a fiber laser with an emission wavelength of 1.55  $\mu\text{m}$  and a pulse width of 400 fs was illuminated from the backside of the substrate [4, 5].

## 3. Results and discussion

Figure 3 plots typical drain-current voltage characteristics for InAs-PHEMTs at room temperature (RT). Note that the figure indicates good pinch-off behavior, with the value of the threshold voltage ( $V_{th}$ ) being about -0.35 V.

Figure 4(a) shows the optical response characteristics for InAs-PHEMTs at  $V_{GS} = 0$  V for fourteen value of  $V_{DS}$ . A digitizing oscilloscope measures the transient

characteristics of induced photocurrent by the change in output voltage through its 50- $\Omega$  input resistance ( $V_{out}$ ). The  $V_{out}$  decreased exponentially but clearly have two gradients at  $V_{DS}$  of 1.4 V. Figure 4(b) shows the logarithmic plot of the result shown in Fig. 4(a) at  $V_{GS} = 0$  V and  $V_{DS} = 1.4$  V. The result clearly shows that the measurement data consist of two components whose lifetimes are different. Therefore  $V_{out}$  due to the optical response of the HEMTs can be expressed as;  $V_{out} = A_1 \exp(-t/\tau_1) + A_2 \exp(-t/\tau_2)$  where  $A_1$  and  $A_2$  are constants.

Figure 5 shows  $\tau_1$  and  $\tau_2$  as functions of  $V_{DS}$ . Although  $\tau_1$  is almost constant at  $V_{DS}$  exceeding 0.8 V, it increases with decreasing  $V_{DS}$  below 0.7 V. On the other hand,  $\tau_2$  does not depend on  $V_{DS}$ . Holes photo-generated transit from the channel to the source under the channel field and accumulate at the source region [6, 7]. Electrons continue to transit across the channel toward the drain until a hole reaches the source and recombines with an electron there. In this case, the lifetime of electrons is given by the time for a hole to transit from the channel to the source region ( $\tau_h$ ) [9]. From the above considerations, we infer that (1)  $\tau_1$  is given by  $\tau_h$  and (2)  $\tau_2$  is given by the Auger recombination lifetime ( $\tau_A$ ), which is discussed later, because it does not depend on  $V_{DS}$ . The reason why  $\tau_1$  increases with decreasing  $V_{DS}$  below 0.7 V is that the drift velocity of holes ( $v_d$ ) is less than the saturated value ( $v_{sat}$ ) and is proportional to the channel field. At  $V_{DS}$  exceeding 0.8 V,  $v_d$  of holes reaches  $v_{sat}$ .

The minimum value of  $\tau_1$  was  $3.5 \times 10^{-11}$  s. The distance for a hole to transit across the channel equals the gate length  $L_g$  (0.7  $\mu\text{m}$ ) and  $v_{sat}$  of holes is estimated to be  $2.8 \times 10^6$  cm/s [10]. Using the above values,  $\tau_h$  of holes was calculated to be about  $3.0 \times 10^{-11}$  s. This value agrees well with  $\tau_1$  determined experimentally at  $V_{DS}$  exceeding 0.8 V.

Next, we estimate the Auger lifetime ( $\tau_A$ ) using Fermi-Dirac statistics and the k-p band theory by Kane [11]. In InAs with the spin-orbit splitting energy comparable to the band gap, the Auger recombination including the process from the heavy hole band to the spin split-off band (CHSH process) is predominant [12]. However, the calculations done in Ref. [12] are based on Boltzmann statistics and hence are incorrect in the region where carriers degenerate. The transition rate (R) based on the CHSH process can be written [13] as;

$$R = 2 \frac{2\pi}{\hbar} \left( \frac{1}{8\pi^3} \right)^3 \iiint d^3\mathbf{k}_1 d^3\mathbf{k}_2 d^3\mathbf{k}'_1 d^3\mathbf{k}'_2 P |M|^2 \\ \times \delta(E_1 + E_2 - E'_1 - E'_2) \delta(\mathbf{k}_1 + \mathbf{k}_2 - \mathbf{k}'_1 - \mathbf{k}'_2)$$

where  $\mathbf{k}_1$  and  $\mathbf{k}_2$  are the wave vectors of electrons in the conduction band (C), and  $\mathbf{k}_1'$  and  $\mathbf{k}_2'$  correspond to the wave vectors of holes in the valence band (H) and the spin split-off band (S). In addition, the net recombination can be obtained by subtracting the inverse process from the normal process. The details of the theory and the calculation procedure are described in Ref. 5. By letting  $\Delta n$  the injected carrier concentration,  $\tau_A$  is defined as  $\tau_A = \Delta n/R$ .

Figure 6 shows the calculated results of  $\tau_A$  as functions of the sheet hole concentration,  $p_s$  for five value of electron concentrations,  $n_0$ . As shown in the figure,  $\tau_{\text{CHSH}}$  is  $3.5 \times 10^{-11}$  sec at  $p_s = 3.0 \times 10^{12}$   $\text{cm}^{-2}$  and  $n_0 = 2 \times 10^{18}$   $\text{cm}^{-3}$ , corresponding to the 2DEG concentration in InAs-PHEMTs. The theoretical result agrees well with the experimental one.

### 3. Conclusions

InAs-PHEMTs exhibited an ultra-fast optical response. The experimental results can be explained successfully using two different lifetimes, one being dominated by the time for a hole to transit from the channel to the source region under the channel field and the other dominated by the Auger recombination. To numerically understand the optical response, we estimated the minority carrier lifetime by using Auger recombination theory. The theoretical result agrees well with the experimental one.

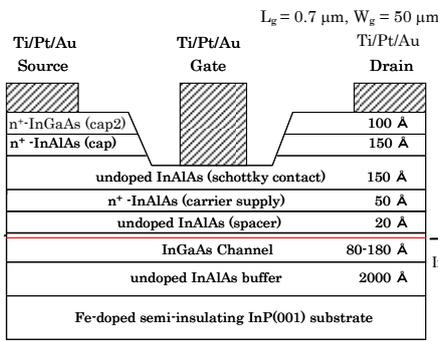


Figure 1 The InAs-PHEMT structure.

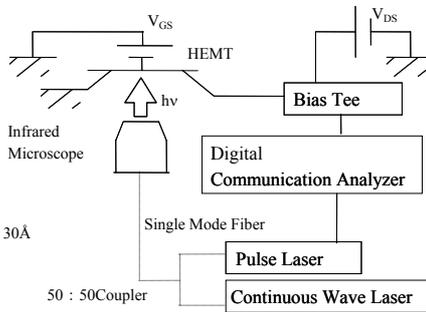


Figure 2 The experimental setup.

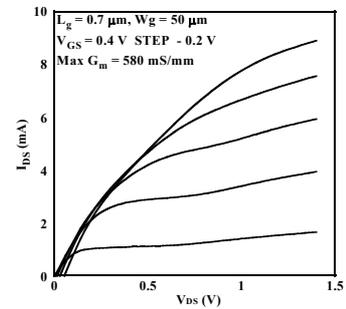


Figure 3 Typical drain-current voltage characteristics for InAs-PHEMTs at room temperature.

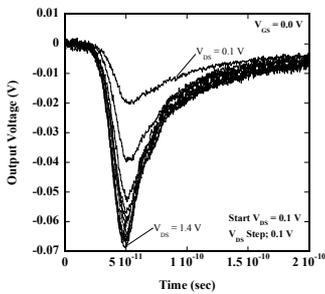


Figure 4(a) The optical response characteristics for InAs-PHEMTs at  $V_{GS} = 0$  V for fourteen value of  $V_{DS}$ .

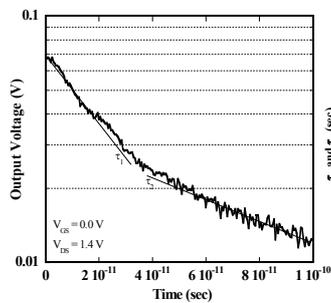


Figure 4(b) The logarithmic plot of the result shown in Fig. 4(a) at  $V_{GS} = 0$  V and  $V_{DS} = 1.0$  V.

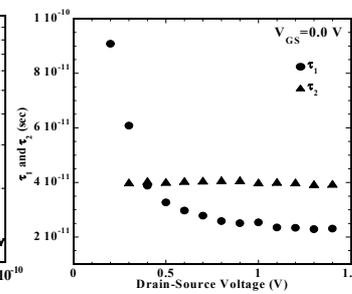


Figure 5  $\tau_1$  and  $\tau_2$  as functions of  $V_{DS}$ .

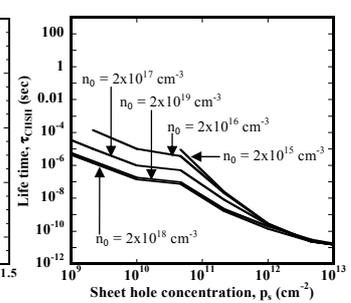


Figure 6 The theoretical result of  $\tau_{\text{CHSH}}$  as functions of sheet hole concentration,  $p_s$  for five value of electron concentrations,  $n_0$ .

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